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IN THE ABSTRACT

Please replace paragraph [0001] of the specification with the paragraph given below:

[0001] This invention relates to the field of integrated circuit fabrication. More particularly, this invention relates to optimizing the operational parameters of inspection equipment used during integrated circuit fabrication. The U.S. Government has a paid-up license in this invention and the right in limited circumstances to require the patent owner to license others on reasonable terms as provided for by the terms of contract 70NANB0H3038, awarded by NIST.

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IN THE ABSTRACT

Please replace the abstract of the specification with the abstract given below:

A method of tuning an inspection system. Characteristics of a An inspection piece ~~are-is~~ sensed and analyzed to identify anomalies ~~having level information~~. The ~~the~~ Level information is analyzed with an initial set of thresholds ~~of inspection system parameters~~, and an initial portion of the anomalies are flagging as defects. ~~A summary of the flagged anomalies is displayed, and an operating curve of potential flagged defects versus threshold for at least one of the inspection system parameters is also displayed.~~ The ~~at least one of the inspection system parameters is selectively~~ are changed to form a modified set of thresholds, and the level information of the anomalies is analyzed with ~~the-a~~ a modified set of thresholds. ~~An updated portion of the anomalies is~~ are flagged as defects based on the immediately preceding analysis of the level information, ~~and a summary of the flagged anomalies is displayed along with the recomputed operating curves.~~ The steps of selectively changing the thresholds and reflagging the defects are repeated as desired, and the modified set of thresholds ~~of the inspection system parameters~~ are stored for use in an inspection system recipe.